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<<纳米技术中的显微学手册>>

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内容概要

现代显微学在纳米技术领域的研究和发展中起到“眼睛”和“手”的功能。
迄今，人们仍在孜孜不倦地寻找纳米尺度上的“火眼金睛”。
本手册的目的在于提供关于各种显微学的原理及其在该迅猛发展的领域内应用的综述参考书。
本手册共有22个专题，每一专题都由不同研究领域的、处于世界前沿的科学家撰写。
本书是第2卷，叙述的是电子显微学的内容，共有12个专题。
本书力图使读者对所叙述的方法有一个概念上的理解，而不是只停留在对理论的堆砌上。
在每一个专题里，都会叙述相关的实例及其应用并加以讨论，使读者对电子显微技术能明了和理解；还会进一步展示各章之间的内在联系，表明每一种技术如何在综合性的、复杂的测试中各自扮演独特的角色，解决具体的问题。

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